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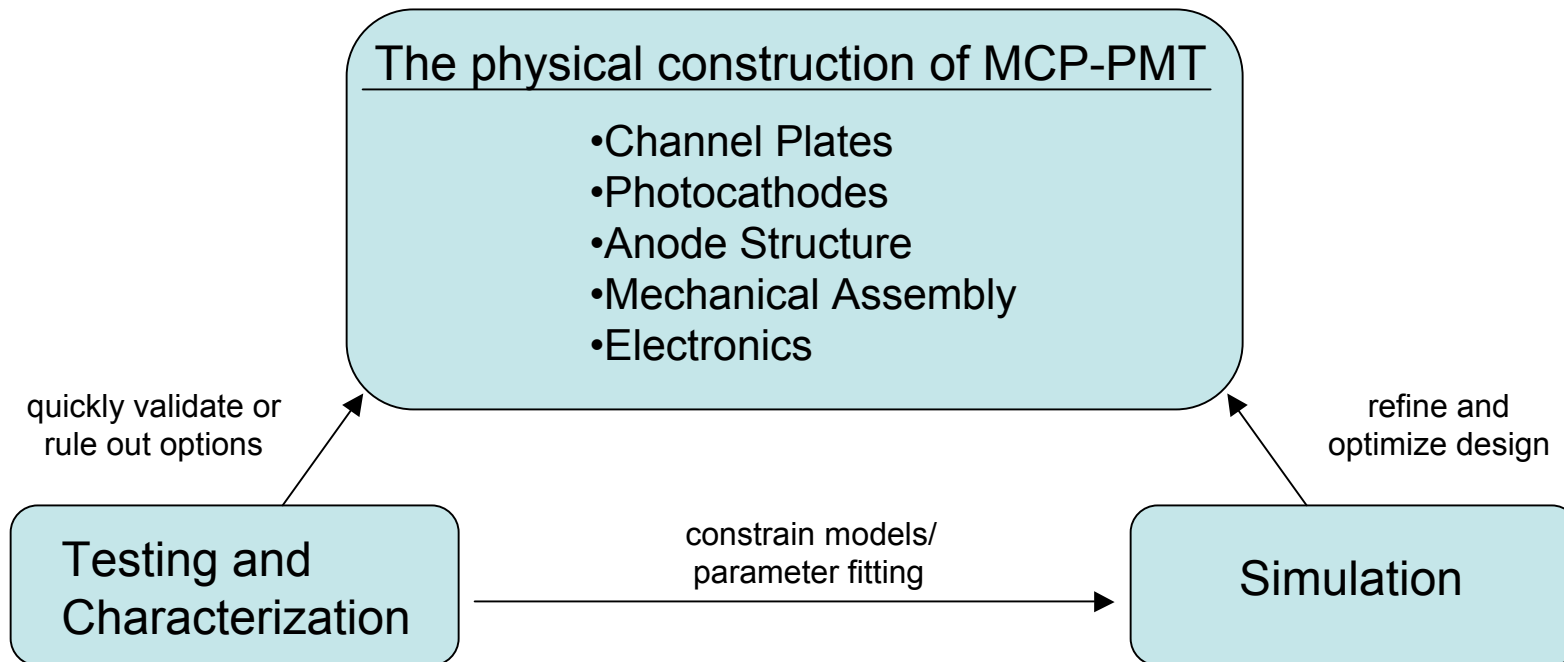
**Office of
Science**
U.S. DEPARTMENT OF ENERGY

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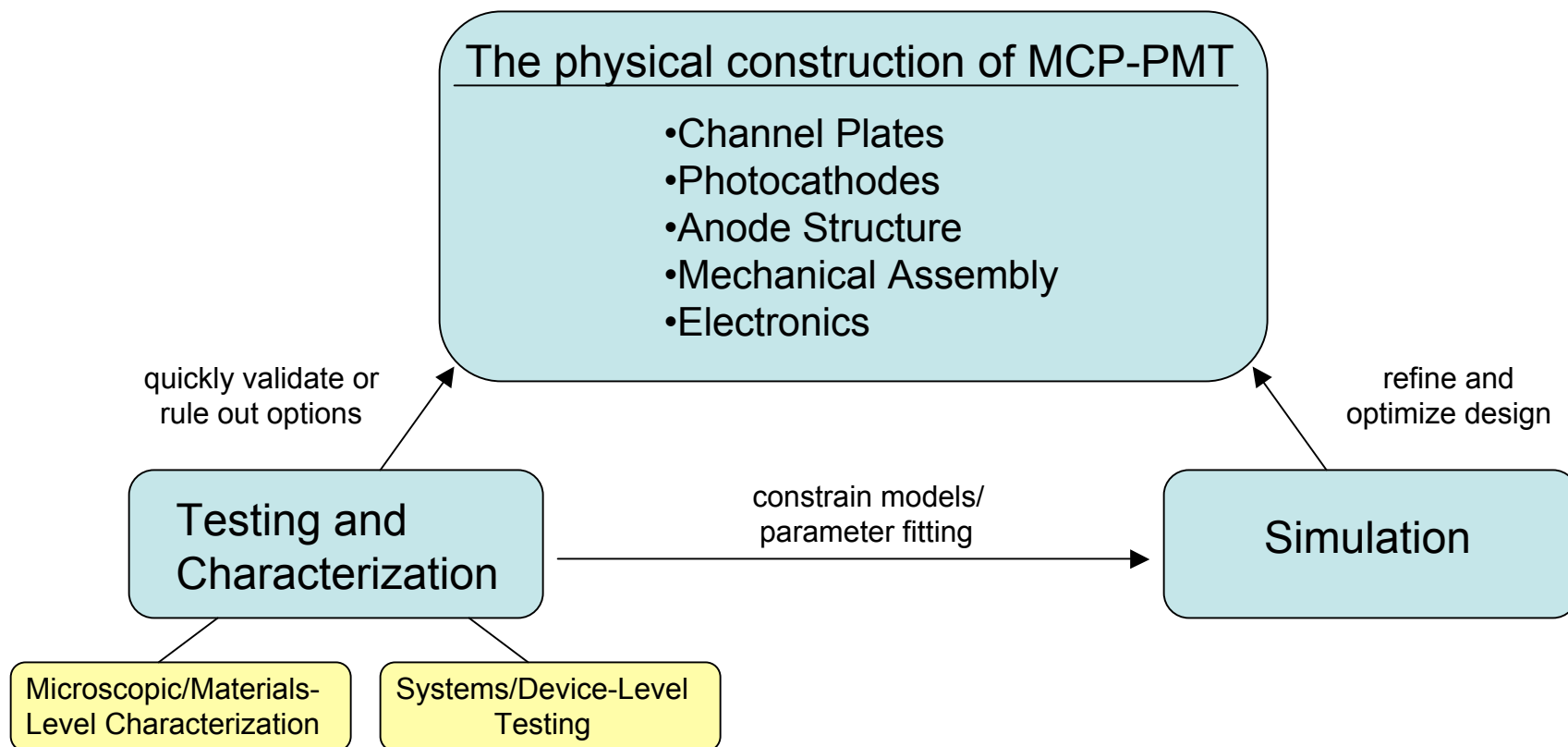
Channel Plate Testing and Systems Integration At the Advanced Photon Source

Microchannel Plate group, LAPPD Collaboration

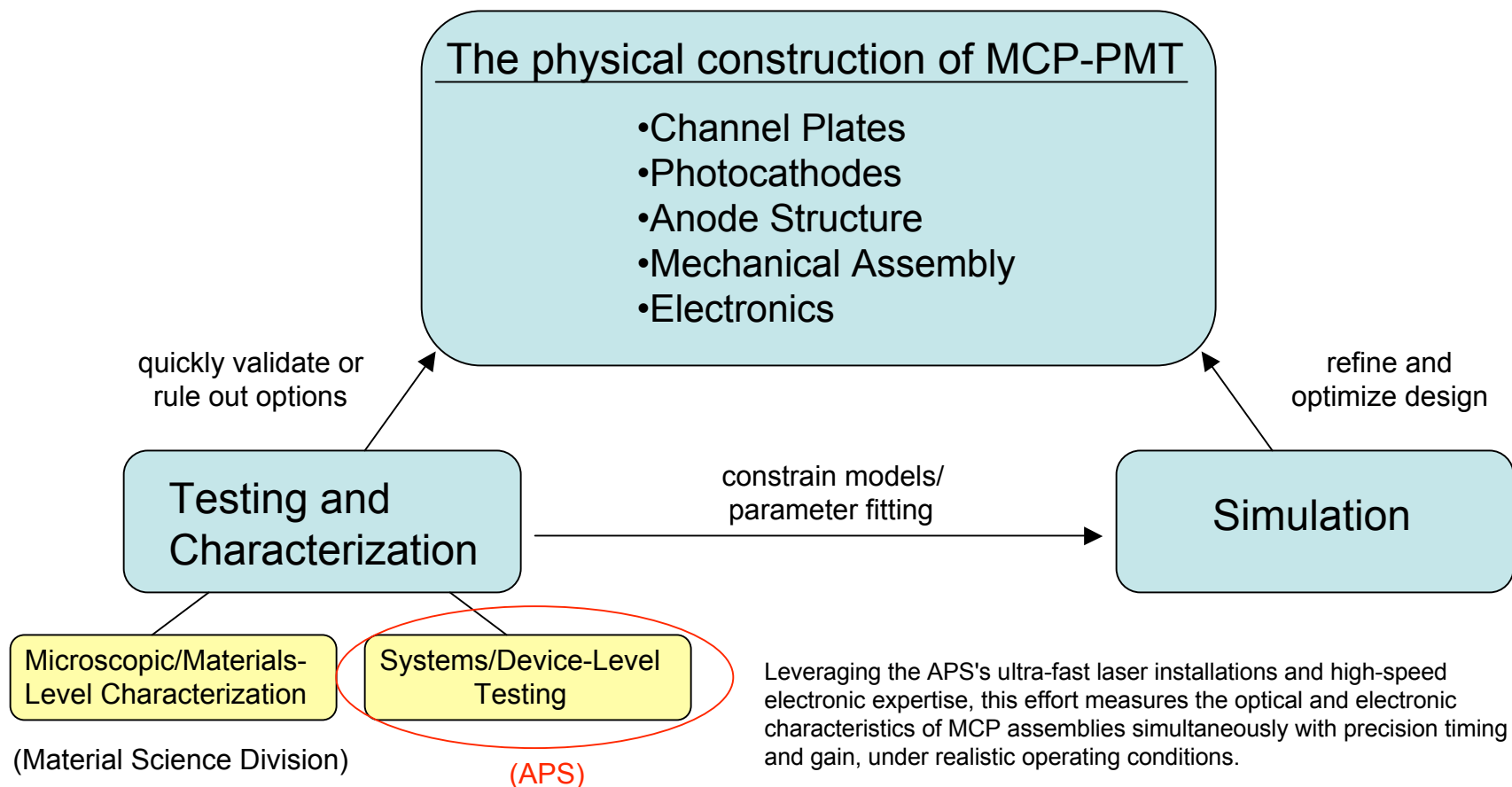
Goals of the APS Test Stand



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Goals and Capabilities

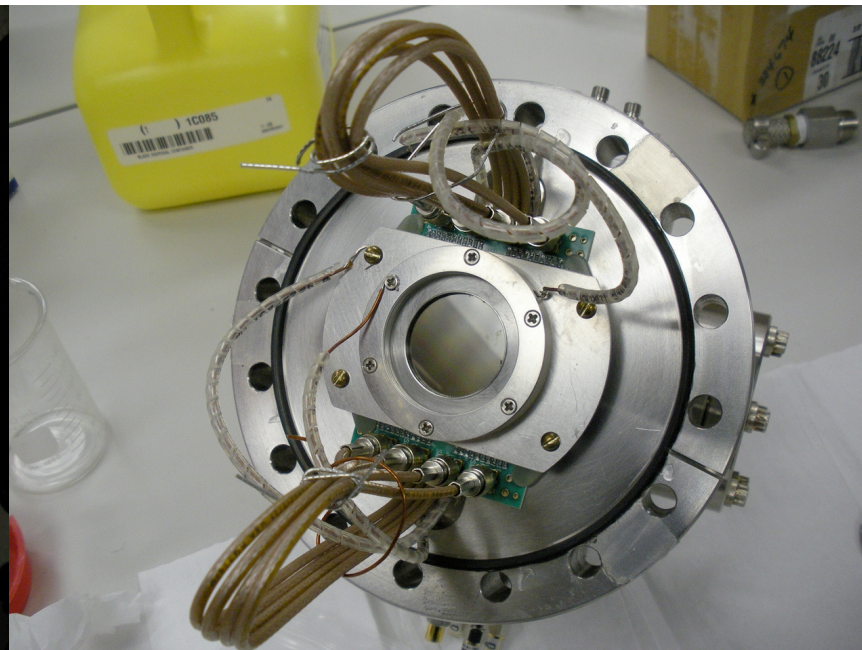
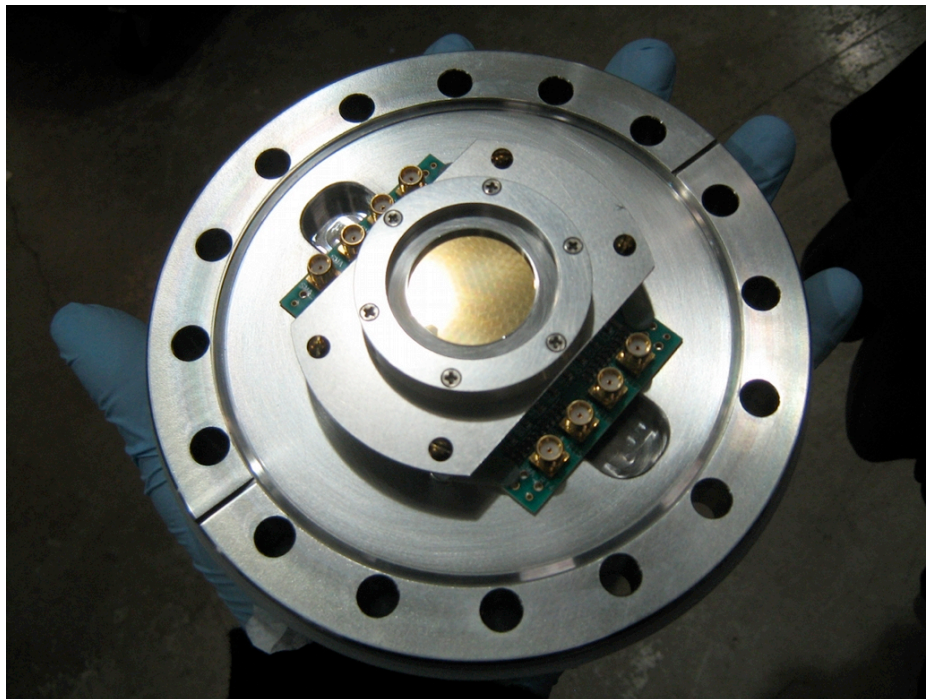
- Develop Operational Experience
 - Working with ALD functionalized MCPs
 - Working with stripline anode structure similar to final product
- Figure out what MCP recipes work (and don't work)
- Basic MCP characterization for Chevron pairs
 - Photon counting, pulse height distributions, amplification curves
 - Image profile, position resolution, signal shape, uniformity
 - I/V curves, dark current, technical issues
- Advanced Characterization in the time domain
 - Transit time spread, arrival time, first strike problem
- Full sized testing



What we don't focus so much on...

- Single plate characterization (we're in photon counting, ie saturation mode)
- Current based measurements
- Fundamental material-level analysis (well, maybe some...)
- Lots of fine variations in samples (turn-over too slow)

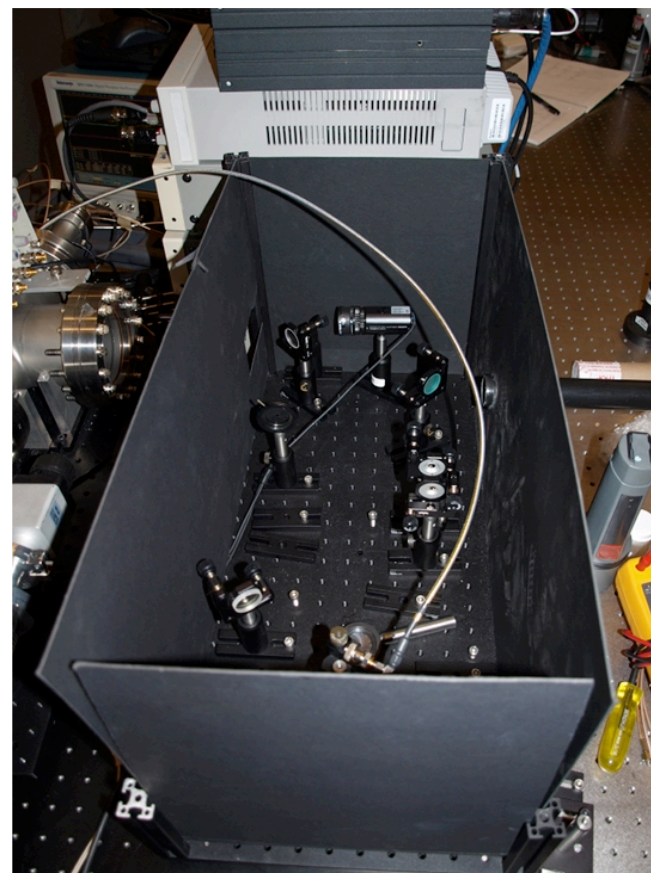
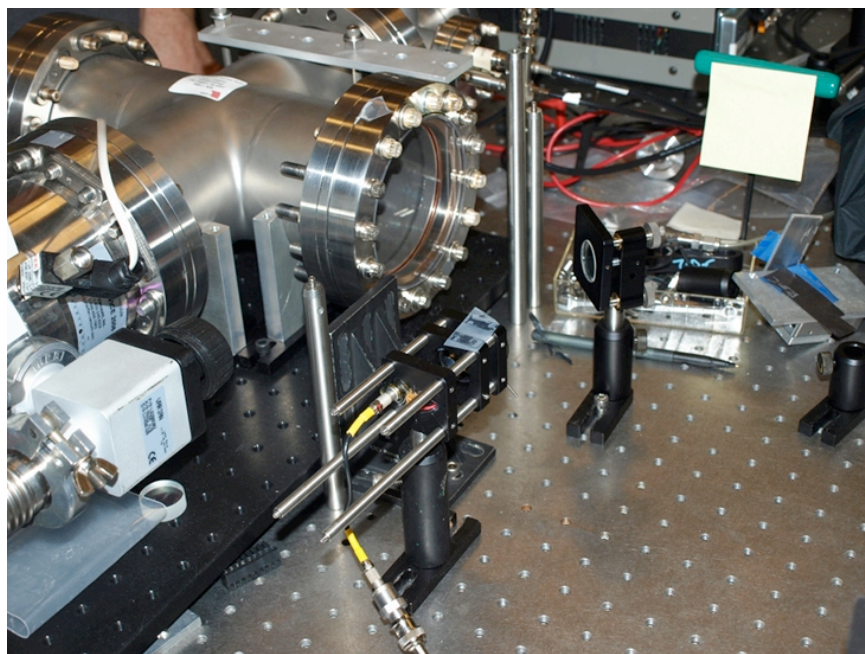
Setup



- Mobile experimental table
- 4-vacuum cross w/ large turbo pump, ion guage, window
- Compact, removable flange with sample holder, anode board, SMA/HV feedthroughs

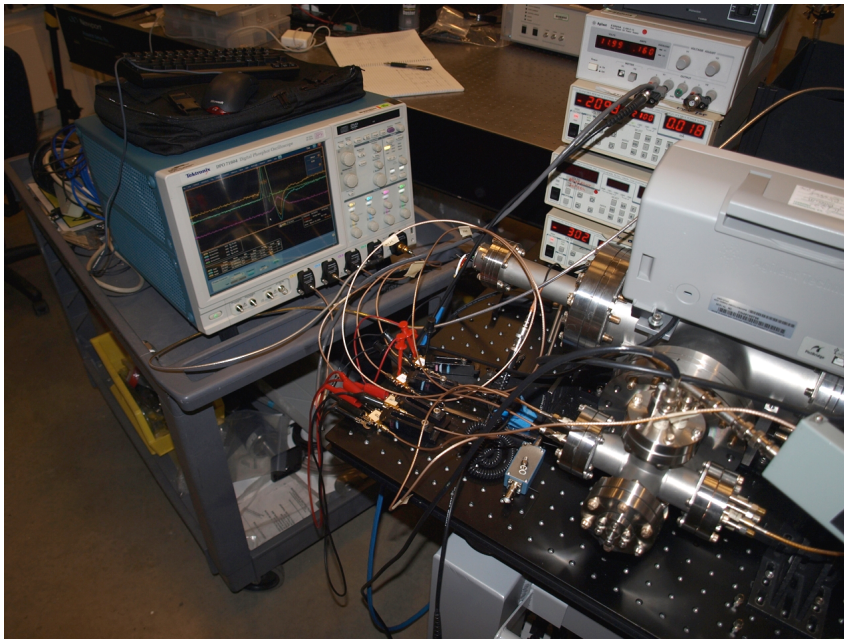
Setup

- Ultra-fast (femto-second pulses, few thousand Hz) Ti-Sapphire laser, 800 nm, frequency triple to 266 nm
- Small UV LED
- Modular breadboards with laser/LED optics



Setup

- Ultrafast electronics: scopes, amplifiers cabling

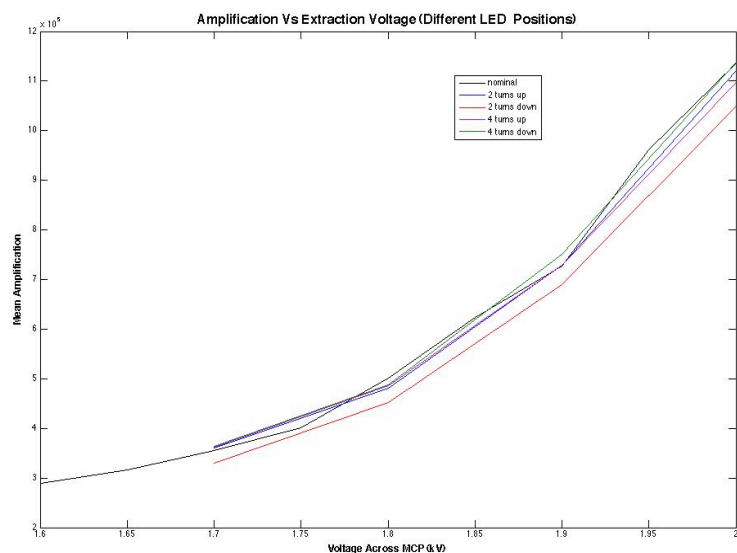




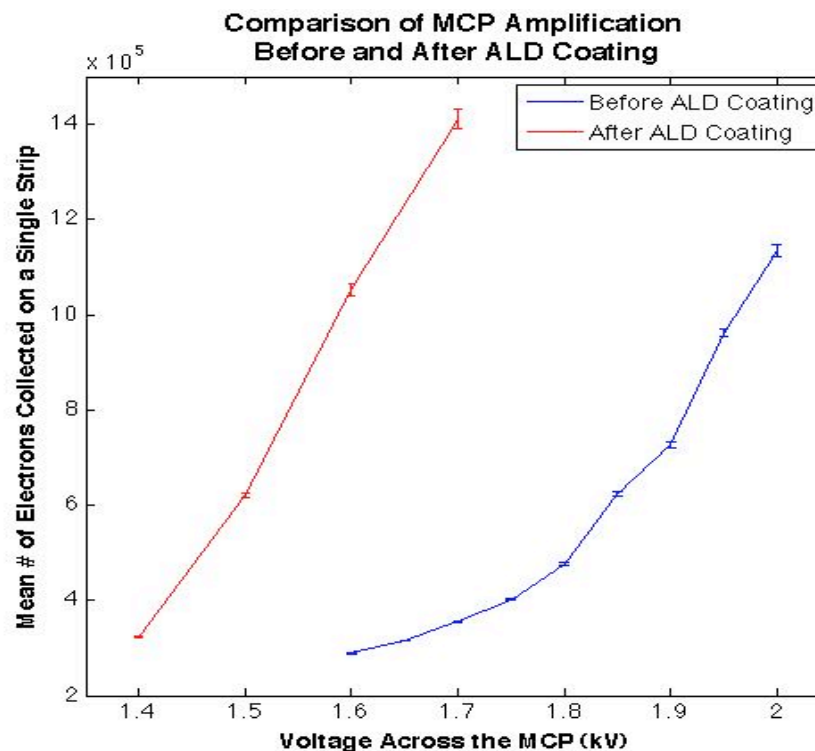
Accomplishments

- A working characterization system from nothing.
- Developed methodology for LED and laser based MCP measurements
- Demonstration of enhanced amplification with high SEE ALD coating on commercial MCP.
- First measurements of a working Argonne MCP pair.
- Stronger collaboration with fabrication, simulation, and testing groups.
- Faster turn-around and feedback.

Accomplishments: SEE Enhancement

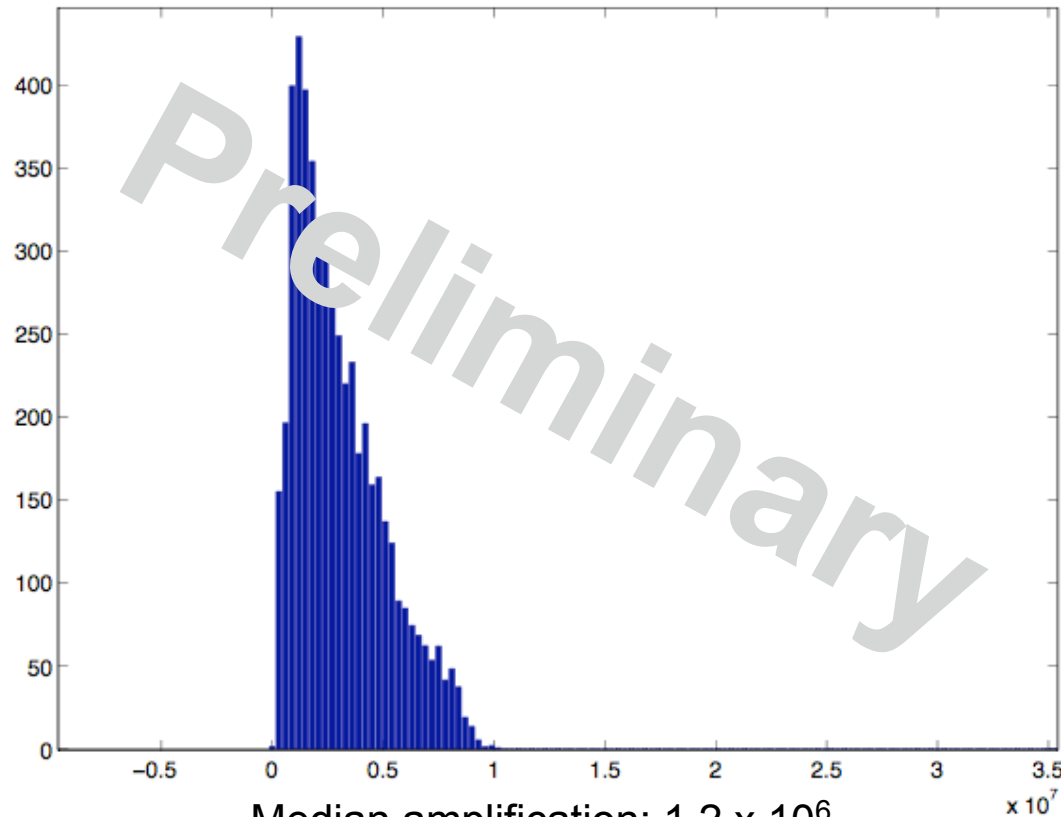


- After characterizing the Photonis MCP, we coat the plates with 10 nm Al_2O_3 .
- The “after-ALD” measurements have been taken without scrubbing.
- These measurements are ongoing.



Accomplishments: MCP 64/65

Pulse Hight Distribution for MCP 64/65 Chevron at 1.3 kV per Plate

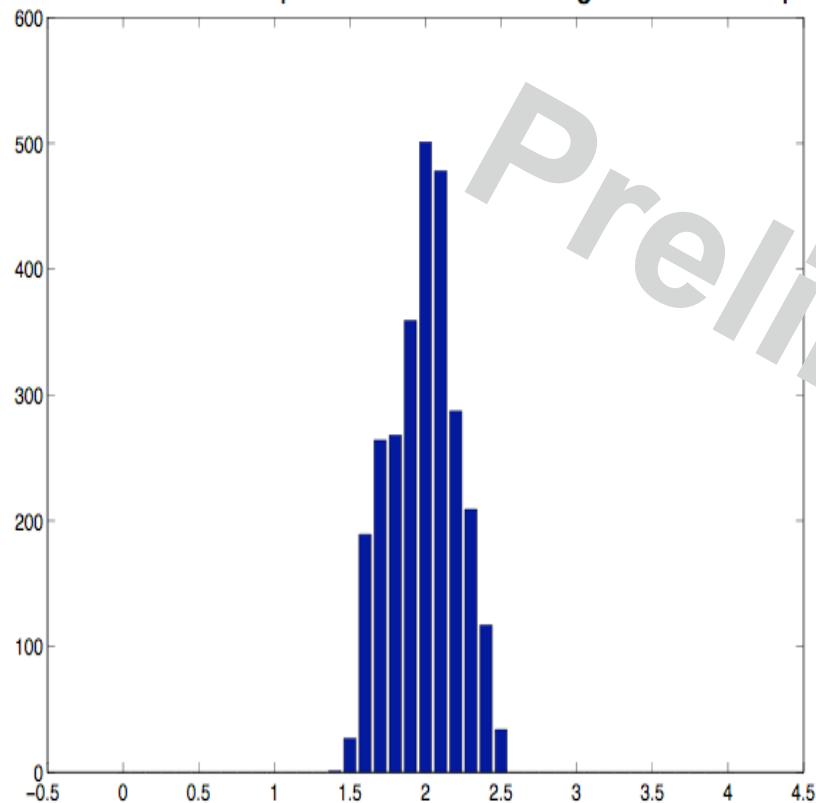


Median amplification: 1.2×10^6

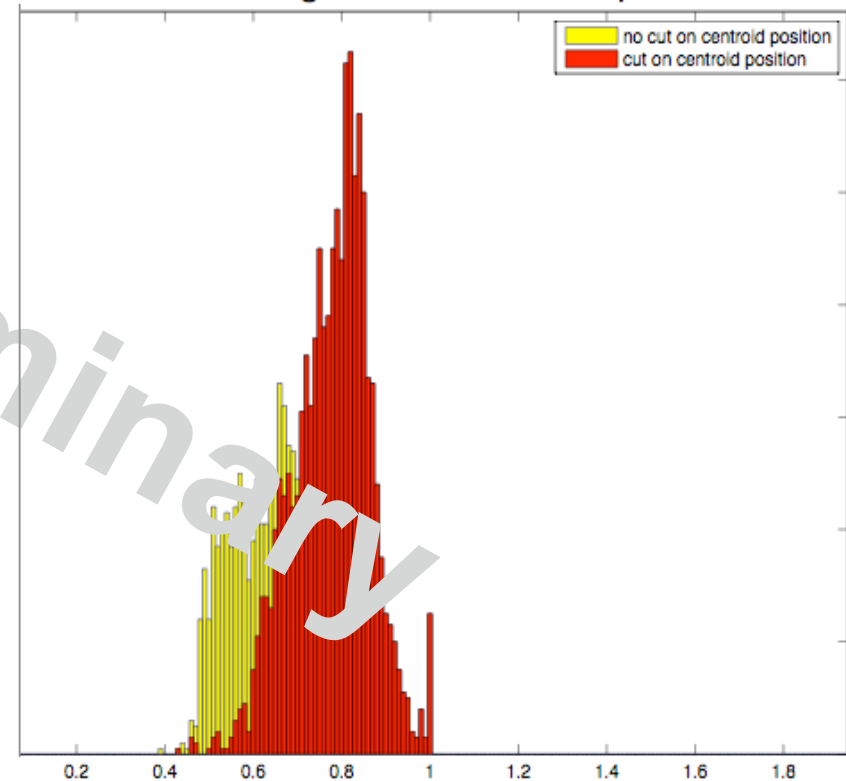
Mean amplification: 5.7×10^6

Accomplishments: MCP 64/65

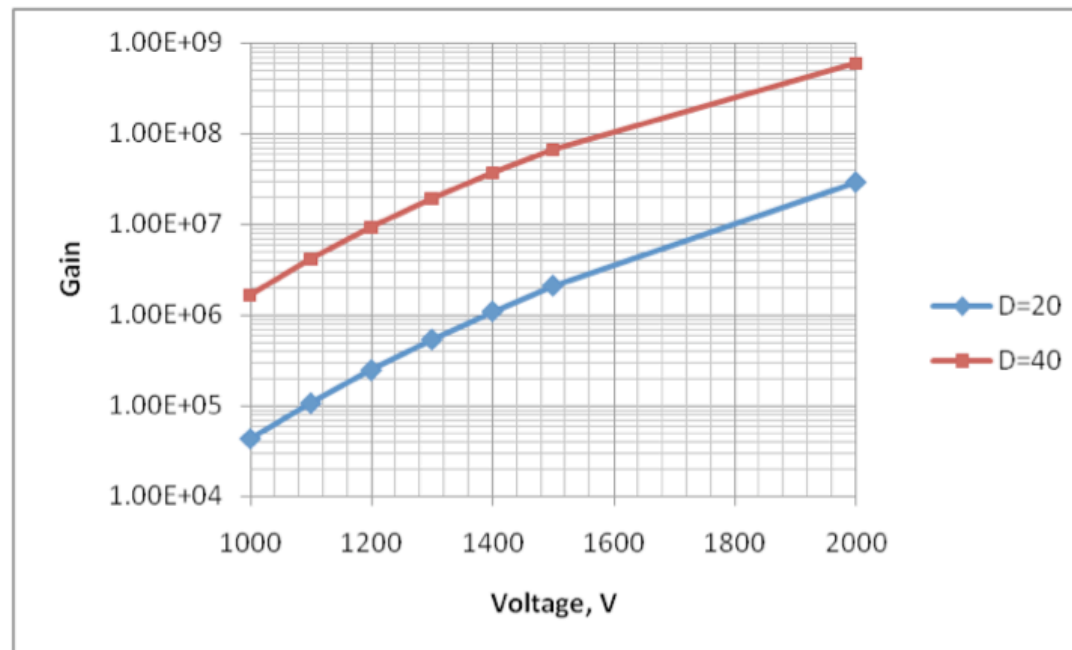
Centroid Position in Stripline # For Evts With Signal Max on Stripline 2



Fractional Charge on Maximum Stripline

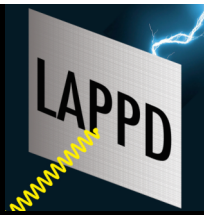


Accomplishments: MCP 64/65



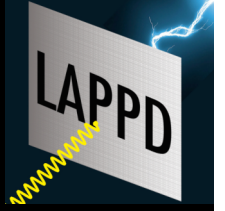
Gain vs. MCP voltage. Blue – D=20 μ m, L/D=60; Brown – D=40 μ m, L/D=40.

Pore coating Al₂O₃, Sigma_{max}=6.23, U_{max}=550V.



Technical Lessons Learned

- Proper handling and assembly of MCPs
- Methodology for single PE mode with laser and LED
- Sparking
 - Avoidance
 - Proper electrode coating
 - Avoiding edge effects
 - Avoiding inappropriate materials (like solder)
 - Staying comfortably below 3 kV
 - Don't reuse plates that have already sparked (new)
 - Protection
 - Load resistor or inductor in series with HV (reduce spark magnitude)
 - When possible, pulsed HV
 - Sacrificial amps
 - Slow ramp up with pauses
 - Discipline in unplugging SMA cables



Turnover

- 1 hour, sample preparation
- 3-4 hours pump down
- 2.5 hours to do measurement
- 1-2 hours offline analysis, proofreading



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 - this will improve with better vacuum compatibility
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- 1-2 hours offline analysis, proofreading
 - Can be done while pumping-down next sample



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Right now, we're looking at about a day per sample... Eventually we can get that down to 2 samples a day... Undergrad labor might help?

MCP Lessons Learned

- A 50 M Ω resistive coating, using Anil's chemistry, with Al₂O₃ works!
- Lower resistances (20 M Ω) might have thermal runaway problems.
- MgO SEE coating seems to be field emitting (high dark current rates)
- Some difficulties with very high resistances (saturation?)



Next Steps: Short Term (now-June)

- Press ahead on basic ALD tests, refine questions/reduce phase space
 - Can we make MgO work?
 - Comparisons of various resistances...
 - Electrode on top vs. bottom?
 - Qing's vs Anil's chemistry?
 - Verify geometric dependences (40 vs 20 microns, spacing...)
 - Baseline comparison with commercial pair
 - Annealing?
 - Scrubbing?
- Work on readying full B-flange setup



Next Steps: Specific tests

- 3 plates with identical 50 M Ω resistive coating (Anil's), two with Al₂O₃ SEE coating, one with MgO.
 - Re-measure Al₂O₃ pair, swap MgO plate with top/bottom plate
- Swap in one identical plate with electrode coating *under* ALD. Test a pair (when photocathode is available)
- Two Variations in thicknesses of SEE coating/resistive coating
- Redo commercial tests as baseline.
- Reexamine, low resistance plates, identical to working 50 M Ω plates. Still runaway currents? of higher resistance plates.

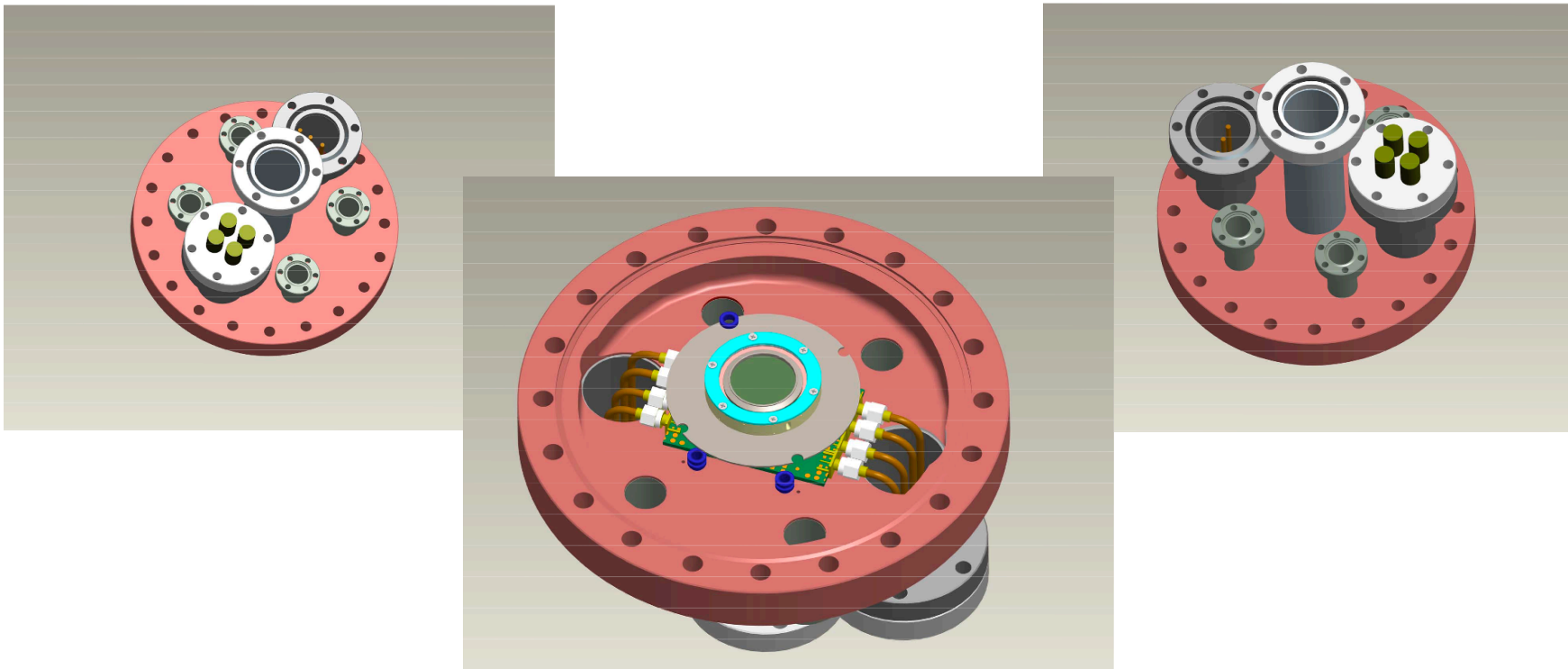


Next Steps: Questions for other groups

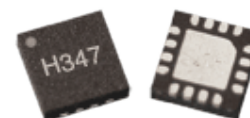
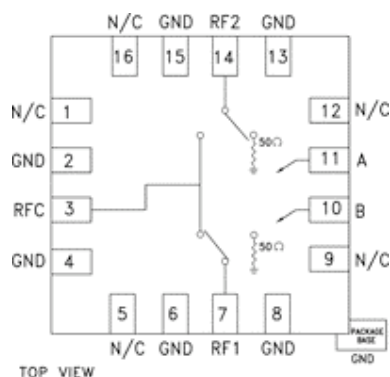
- Simulations on the effect of gaps (simulation group)
- Sensitivity to secondary emissivity (simulation group)
- Failure analysis of broken MCPs (ALD group)
- Thermal coefficient of resistivity tests (with cooling and heating), before and after annealing (ALD group)
- Better understanding of SEE properties (materials characterization group)
- Morphology questions (?)

Next Steps: Medium Term (summer+)

- Completed B-Flange



Next Steps: Medium Term



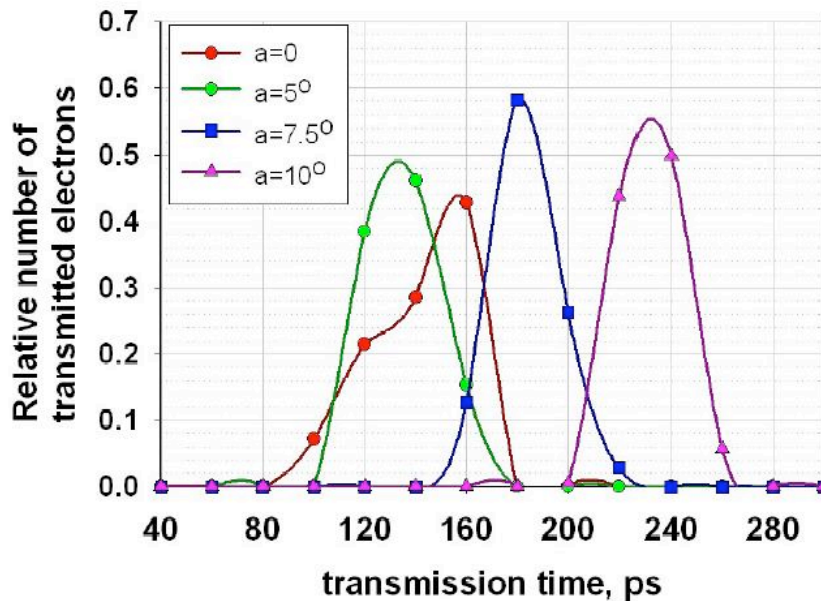
- Automation...
 - Motorized mirror mounts
 - Computerized scope acquisition
 - Relaying between input channels
 - Computer controlled HV
 - Tying it all together (labview?)

Next Steps: Medium Term

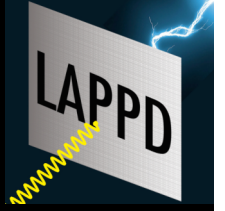
- Laser timing measurements

Transit Time Spread (TTS)

Comparison of TTS for direct and tilted channels



Z. Yusov, S. Antipov, Z. Insepov (ANL),
V. Ivanov (Muons, Inc), A. Tremsin (SSL/Arradance),
N. Sullivan (Arradance)



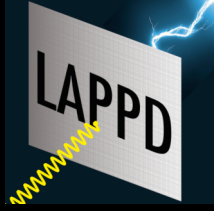
Remaining Technical Issues/Work

- Making a photocathode
- Spacing the MCPs
- Rigid, vacuum compatible SMAs
- Automating the measurement process
- Completion of the B-flange



Next Steps: Long Term (year 2+)

- 8" x 8" testing, pseudo-complete glass(?) assembly, welded onto a large flange
- Readout all channels using LAPPD-designed electronics
- For quality control and to test data acquisition methods



Conclusions

- We have successfully assembled the right resources, man-power, expertise, and experience necessary to meet our testing goals.
- Some early successes are encouraging.
- We're just about over the hump - starting to move quickly on finding working recipes, have some good leads...
- Now is a critical time.
- In the near future, we hope to have publishable results.